



NV-3200 Surface Profiling System

Accurate Non-Contact Surface Topography

Superior non-destructive 3D Surface Profiling and Analysis

Easy-to-Use Platform Delivers Rapid and Efficient Process Monitoring

Comprehensive and Intuitive software Provides Sample and Application Flexibility

Specification

Measuring method	White-Light Scanning Interferometry(WSI), Phase Shift Interferometry(PSI)
F.O.V Lens	4 Position Motorized Turret Addition F.O.V Available (Option)
Scanning Range	MAX 270um (PZT Scanning)
Scanning Velocity	12um/sec (1x~5x user-selectable)
Vertical Resolution	WSI : < 0.5nm / PSI : < 0.1nm
Lateral Resolution	0.2 ~ 4um (Objective Lens Dependent)
Illumination	White-light LED Illumination
Tip / Tilt	Probe Tip/Tilt $\pm 9^\circ$ Motorized
Interferometric Objectives	5Lens Available (Motorized Turret)
Step Height Repeatability	0.1% @1 σ (Standard Sample 8um)
X,Y Stroke	300x300mm (Motorized)
Z Stroke	100mm (Motorized)
Stage Size	445x445mm

Option

F.O.V Lens	0.55x, 0.75x, 1.0x, 1.5x, 2.0x (Selectable)
Interferometry Objectives	2.5x, 5x, 10x, 20x, 50x, 100x (Selectable)
Scanning Range	Max 10mm available (Motor Scanning)
Vaccum Stage	Option



NanoSystem Co., Ltd.

90, Techno 2-ro, Yuseong-gu, Daejeon 305-509, Korea

Tel: 82-(0)42-717-2451 Fax:82-(0)42-335-2410

Mobile:82-(0)10-2505-8844 Email: thkim@nanosystemz.com

Homepage:www.nanosystemz.com